



## [WeF1] Processing for AI Semiconductor Modules

<b>Session Date</b>	November 12 (Wed.), 2025
<b>Session Time</b>	09:00-10:35
<b>Session Room</b>	Room F (Panorama Room, 16F)
<b>Session Chair</b>	Prof. Hongyun So (Hanyang Univ., Korea)

### [WeF1-1] [Plenary]

09:00-09:45

#### Status of AI Packages and Its Manufacturing Issues

Seungbae Park (State Univ. of New York at Binghamton, USA)

### [WeF1-2] [Invited]

09:45-10:15

#### Challenges of Hybrid Cu Bonding for High Bandwidth Memory

Jaewha Park, Byengjun Lee, Ilyoung Yoon, Cheolhyun Lim, and Kwangjin Moon (Samsung Electronics Co., Ltd., Korea)

### [WeF1-3] [Invited]

10:15-10:35

#### Cu Post Bonding Technology, based on Laser-Assisted Bonding with Compression (LABC) and Fume-Free Laser Solder Paste for Advanced 3D Interconnections

Kwang-Seong Choi, Jiho Joo, Gwang-Mun Choi, Jungho Shin, Chanmi Lee, Ki-Seok Jang, Jin-Hyuk Oh, Ho-Gyeong Yun, Seok Hwan Moon, Gaeun Lee, Seong Cheol Kim, Yong-Sung Eom (ETRI, Korea), Geunsik Ahn, and Youn Sung Ko (PROTEC Co., Ltd., Korea)